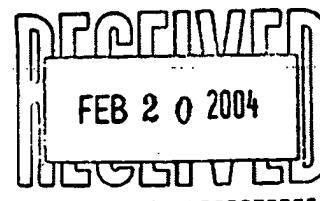


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 09/212,726  
Filing Date ..... December 15, 1998  
Inventor..... Klaus F. Schuegraf  
Assignee..... Micron Technology, Inc.  
Group Art Unit..... 2813  
Examiner ..... Kielin, Erik J.  
Attorney's Docket No. ..... MI22-1098  
Title: Semiconductor Processing Methods of Chemical Vapor Depositing SiO<sub>2</sub> on a Substrate

**RESPONSE TO OCTOBER 17, 2003 FINAL OFFICE ACTION**  
**TO ACCOMPANY RCE FILING**

To: Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450



From: Jennifer J. Taylor, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)  
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**AMENDMENTS**

**Introductory Comments**

In reply to the final office action dated October 17, 2003, applicant amends and remarks as follows.